

Docket No.: 49657-961



*Jfw* 2882  
*2882*  
*2882*  
PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of : Customer Number: 20277  
Kenji ITOGA, et al. : Confirmation Number: 5521  
Application No.: 09/769,490 : Group Art Unit: 2882  
Filed: January 26, 2001 : Examiner: C. Kao  
For: X-RAY EXPOSURE APPARATUS, X-RAY EXPOSURE METHOD, X-RAY MASK,  
X-RAY MIRROR, SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON  
RADIATION METHOD AND SEMICONDUCTOR DEVICE

**AMENDMENT**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

The following Amendment and Remarks are submitted in response to the Office Action  
dated April 13, 2004.

08/13/2004 EABUBAK1 00000121 500417 09769490

01 FC:1201 344.00 DA